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EHF 2001,0167 P



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By: 

Date: September 22, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 09/873,230 Confirmation No. 4487

Applicant : Norbert Benesch et al.

Filed : June 4, 2001

TC/A.U. : 2625

Examiner : John B. Strega

Title: : Method and Device for Optically Monitoring  
Fabrication Processes of Finely Structured  
Surfaces in a Semiconductor Production

Docket No. : EHF 2001,0167 P

Customer No. : 24131

Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

S i r :

In response to the Office action dated June 23, 2004, please  
amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of  
claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 15 of this paper.